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## H<sup>-</sup> and D<sup>-</sup> Production Efficiency in a Multi-Dipole ECR-Plasma Source

The ECR negative ion source "Prometheus I"is operated either with high purity H<sub>2</sub> (> 99.999\%) or  $D_2$  > 99.8\%) in order to probe H<sup>-</sup> and D<sup>-</sup> ions, respectively, and examine the effect of the isotope upon their production. These ions are predominantly formed in the plasma bulk by dissociative attachment of low-energy (cold) electrons to highly ro-vibrationally excited molecules which in turn result mainly from the EV process sustained by high-energy (hot) electrons confined in the ECR zones. Langmuir probe and laser photodetachment measurements, realized in the pressure range 1 to 20 mTorr and for deposited power up to 900 W, reveal briefly: (i) higher and only slightly increased cold electron density and temperature in deuterium; (ii) no pronounced difference in the hot electron density and temperature; and (iii) overall a similar negative ion yield (up to  $6 \times 10^{15}$  m<sup>3</sup>. Finally, the  $n_{H^-}/n_e$  ratio is constantly higher than the  $n_{D^-}/n_e$  one.

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